



# INTERNATIONAL STANDARD



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**Semiconductor devices – Micro-electromechanical devices –  
Part 48: Test method for determining solution concentration by optical  
absorption using MEMS fluidic device**

INTERNATIONAL  
ELECTROTECHNICAL  
COMMISSION

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INTERNATIONAL ELECTROTECHNICAL COMMISSION

**SEMICONDUCTOR DEVICES –  
MICRO-ELECTROMECHANICAL DEVICES –**

**Part 48: Test method for determining solution concentration  
by optical absorption using MEMS fluidic device**

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The language used for the development of this International Standard is English.

This document was drafted in accordance with ISO/IEC Directives, Part 2, and developed in accordance with ISO/IEC Directives, Part 1 and ISO/IEC Directives, IEC Supplement, available at [www.iec.ch/members\\_experts/refdocs](http://www.iec.ch/members_experts/refdocs). The main document types developed by IEC are described in greater detail at [www.iec.ch/publications](http://www.iec.ch/publications).

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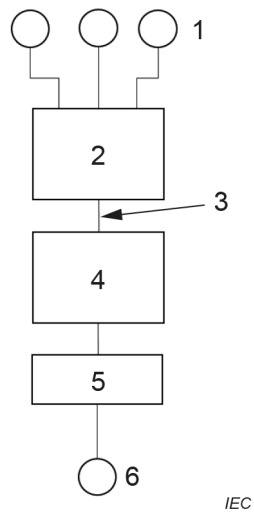
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## INTRODUCTION

A MEMS fluidic device is one of the key devices in MEMS technologies, including bio-MEMS, chemical MEMS, and micro TAS (total analytical system). A MEMS fluidic device, in general, consists of several micro components such as inlet ports for injection of a filtered sample and reagents to induce a sample to have the optical absorption at specific wavelength, a microfluidic mixer for physical mixing, a micro-reactor for chemical or biological reaction, a detection area for determining the concentration of solution using optical source and detector from the outside, as well as outlet ports for waste-out as shown in Figure 1. All components in a MEMS fluidic device are connected with microfluidic channels. In case there is a synthesizing solution with absorption at a specific wavelength in a MEMS fluidic device, it is possible to determine the concentration by using an absorption method at specific absorption wavelength based on the Beer-Lambert law [1]<sup>1</sup>. MEMS fluidic devices are more cost-effective than conventional analysis tools and methods since expensive reagents and human power are used less and in-situ monitoring is enabled.



### Key

- 1 inlet ports
- 2 microfluidic mixer
- 3 microfluidic channel
- 4 micro-reactor
- 5 detection area
- 6 outlet port

**Figure 1 – Schematic drawing of micro components in a MEMS fluidic device (top view)**

<sup>1</sup> Numbers in square brackets refer to the Bibliography.

## **SEMICONDUCTOR DEVICES – MICRO-ELECTROMECHANICAL DEVICES –**

### **Part 48: Test method for determining solution concentration by optical absorption using MEMS fluidic device**

#### **1 Scope**

This part of IEC 62047 specifies the requirements and testing method to determine the solution concentration by optical absorption using MEMS fluidic device.

#### **2 Normative references**

There are no normative references in this document.